

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination CHIU ET AL.	
		Examiner John Juba, Jr.	Art Unit 2872	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-2004/0201889 A1	10-2004	Wang et al.	359/486
	B	US-6,122,103	09-2000	Perkins et al.	359/486
	C	US-4,289,381	09-1981	Garvin et al.	427/163.1
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	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

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	N					
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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Zhaoning Yu, et al., "Reflective polarizer based on a stacked double-layer subwavelength metal grating structure fabricated using nanoimprint lithography", Appl. Phys. Lett., Vol. 77, no. 7, pp. 927-929, 14 AUG 2000.			
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.